

ISSP2005 EXHIBIT

ISSP2005 Committee,
The Vacuum Society of Japan

The ISSP Panel Exhibit*) will be held in conjunction with The 8th International Symposium on Sputtering and Plasma Processes (ISSP2005) at the Kanazawa Kokusai Hotel from June 8 to 10, 2005. It will feature the broad spectrum of equipment, instruments, materials, systems, services, etc. for sputtering and plasma processes. At the last Exhibit, ISSP2005, 23 companies exhibited their offerings, and exchanged the information with over 300 attendees. This is the best opportunity for you to present, face-to-face, your products and services to a vital market. The Panel Exhibit will be opened parallel to ISSP2005 poster presentation at the same room. The ISSP2005 committee requests your company to attend this exhibition as an exhibitor. The up-to-date information can be seen at our web site: <http://issp2005.org/>. Please don't miss the terrific opportunity!



The Panel Exhibit and the Poster Session in ISSP2003

Exhibit Details

[Scope]

Process equipment (sputtering, evaporation, MBE, CVD, etching, etc.)
Analyzer, controller, and measurement apparatus
Related materials and components (Sputtering target, etc.)

[Location and term]

Kanazawa Kokusai Hotel, June 8 to 10, 2005

[Exhibit fee]

¥ 120,000/unit (Japanese yen)

[Special favor]

- *The exhibitor can show one-page (A4 size), monochrome, and camera-ready advertisement on the proceedings for free. Please tolerate that the printing quality is not so high grade.
- *We prepare a link to your home site on our web page, <http://issp2005.org/>, according to your request.

[How to apply]

Please fill the application form and email it to the committee member.

Deadline: April 8, 2005

*) Be careful that the ISSP2005 Exhibit is different from the Manufacturer's Presentation of ISSP2005 which is a technical presentation made by invited manufacturer.

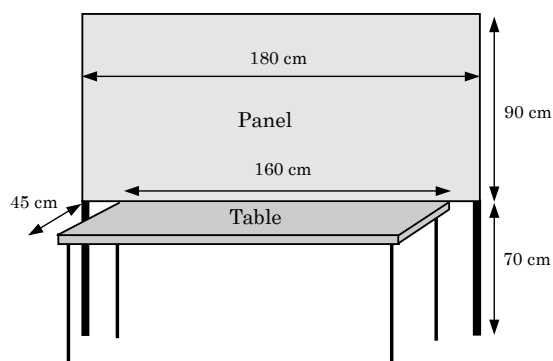
If you want to apply the one-page advertisement on the proceedings, please send a PDF file or a paper-printed copy to the committee member (see the end of this article).

[Policy]

- *Description language is English.
- *At least one person is required to explain the panels. He/she is entitled to attend all the session of ISSP2005 for free.
- *For extra two persons of exhibitor, the registration fee is ¥20,000 per person. From the 4th person and up, please register as a normal participant.
- *The carriage of all the exhibiting materials is to be made by yourself.
- *Don't remove the panel before the closing of ISSP2005.

[Configuration]

- *One unit of exhibition space consists of a panel of about 180 cm (width) × 90 cm (height) and a desk of 160 cm (width) × 45 cm (depth) × 70 cm (height).
- *The total weight of exhibiting materials on the desk should be less than 10 kg.
- *If you need more space, you may use multiple exhibition units by paying additional fee. The acceptance will be informed later.
- *Utilities of electrical power are available for personal computer use. It, however, is limited to 2 A (AC100 V).
- *If you would like to make any special exhibition, please consult with us.



[Questions and Application]

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Exhibitors of the Past ISSP Exhibits

- Advanced Energy Japan
- AIMEC Corp.
- ANELVA Corp.
- ASTECH Corp.
- BOC Coating Technology
- ENI JAPAN Ltd.
- Fraunhofer-Institut für
Elektronenstrahl- und Plasmatechnik
- FTS Corp.
- Hakuto Co., Ltd.
- HITACHI ZOSEN Corp.
- Hüttinger Elektronik GmbH
- JAPAN ENERGY Corp.
- JEOL Ltd.
- Landmark Technology Corp.
- LEYBOLD Co., Ltd.
- MARUBUN Corp.
- Matsubo Co., Ltd.
- MITSUBISHI MATERIALS Corp.
- NANOMETRICS JAPAN
- NIHON VEECO K. K.
- NOA SYSTEMS Inc.
- NTT AFTY Corp.
- OXFORD INSTRUMENTS
- PEGASUS Software Inc.
- SAES GETTERS JAPAN Co., Ltd.
- Sanyu Electron Co., Ltd.
- Science Technology Co., Ltd.
- SHINCRON Co., Ltd.
- SHOWA SHINKU Co., Ltd.
- Singulus Technologies AG
- Sputtered Films, Inc.
- TDY INC.
- ULVAC JAPAN, Ltd.
- UNIVERSAL SYSTEMS Co., Ltd.
- VACUUM METALLURGICAL Co., Ltd.
- VIC International Co., Ltd.
- Von Ardenne Anlagentechnik GmbH